A Novel Purification Process for Used SF₆ From Electrical Installations

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ABSTRACT

In test field studies under highly stressed conditions, one possible toxic SF₆ decomposition product formed is disulfur decafluoride or S₂F₁₀. This paper presents a test facility for the investigation of the destruction of S₂F₁₀ via pyrolysis and the more promising technique of photolysis, specifically photolytic UV destruction. Accordingly, a purification pre-treatment pilot plant was also developed comprising of a photolytic UV reactor for the destruction of S₂F₁₀, gas scrubbers for the removal of hydrolysable SF₆ decomposition products and membranes for the removal of inert gas.

INTRODUCTION

Sulfur hexafluoride (SF₆) is a physically stable, non-toxic and inert gas with high dielectric strength and thermal stability. It is generally used in electrical equipment for power transmission and distribution such as gas insulated circuit breakers, gas insulated transmission lines and gas insulated substations. Despite its excellent properties as an insulating and arc-quenching medium in electrical installations, SF₆ has also been identified as a very strong greenhouse gas.

The SF₆ ReUse Program ^(1,2) provides a closed loop handling initiative aimed at taking back corrupt SF₆ gas from electrical installations thereby minimizing potential emissions. Ultimately, the used gas is fed back into the virgin SF₆ production stream, without pre-treatment. The output therefore fulfills all the requirements of virgin gas according to IEC 376 standard.

The used gas collected from various electrical installations often contains operational impurities such as inert gas, switching dust, moisture and oil. More importantly, used SF_6 gas may contain decomposition products caused by arcing and faults. As long as the concentration of these impurities falls within the specifications for re-introduction into the virgin SF_6 production process stream (SF_6 -ReUse-Specification), the concept of a closed loop system remains fulfilled.

Occasionally, used gas is collected from electrical installations where severe faults were experienced or gas is received from test operations where the degree of contaminants and decomposition products falls outside the ReUse specification. In this case the used SF_6 gas must be disposed of in an environmentally friendly manner, mostly by incineration and at the user's expense. This effectively "breaks" the closed loop handling concept since the used gas is not returned to its virgin state.

In order to keep the loop closed, a purification facility to pre-treat out of specification gas has been developed. The different technologies in existence to remove high concentrations of common impurities such as air, moisture, oil, SO_2 and SO_2F_2 are briefly discussed. Of greater

concern is the potential presence of disulfur decafluoride (S_2F_{10}) due to its toxicological profile and is formed in highly stressed SF_6 discharges.

The investigation and implementation of a purification pre-treatment facility for decomposition products such as S_2F_{10} would complete the SF₆ ReUse program by being able to pre-treat gas that normally would be rejected, so that it can be introduced in the virgin SF₆ production stream.

SF6 PURIFICATION PROCESSES

Table 1 shows the average impurities in used SF_6 recovered from test field operations in 2001. The impurity profile is compared to the IEC480⁽³⁾ specification for used SF_6 . Note that the impurities are further classified into inert, hydrolysable and stable/non-hydrolysable.

Impurity (content)	IEC60480	Average value	Maximum value	Behavior/Property
(SF6)	96.99%	97.17%	99.99%	Inert
Air (O2, N2)	3.0%	1.59%	59.74%	Inert
CF4		1.15%	2.70%	Inert
SO2	50ppm	300ppm	1.4%	Hydrolysable
SO2F2		200ppm	1.5%	Hydrolysable
S2F10	Not mentioned	174ppm	1.55%	Stable/ Non-hydrolysable

Table1Average Impurities in Used SF6 from Test FieldsExceeding the IEC480 Specification in 2001

Gas impurities such as oxygen and nitrogen can be removed by a membrane separation technique where the main gas flow is separated into a permeate stream and a product stream. Membrane separation units are effective at separating gases with different molecule sizes such as SF₆ from N₂ and O₂⁽⁴⁾.

The soluble gas components such as sulfur oxyfluorides, sulfur dioxide, (SO_2) and sulfuryl difluoride (SO_2F_2) can be removed from SF_6 utilizing gas scrubbers. These components have a high solubility in water compared to SF_6 as shown in Table 2. The solubility can be improved even further by using alkaline solutions.

Component	SF_6	CF_4	N_2	O ₂	S_2F_{10}	SO_2	SO_2F_2
Solubility (g/kg H₂O)	0.06	0.04	0.02	0.05		164.1	1.00

Table 2	
Solubility of Different Gases at 10°C and 1.013 Bar ⁽⁵⁻⁸⁾)

Due to its properties, S_2F_{10} is the most challenging to remove. When separated and obtained in a concentrated form, S_2F_{10} presents a waste disposal problem because of its toxicological profile ⁽⁹⁾, as shown in Table 3. It is also evident that S_2F_{10} could dominate the toxicity profile of any given

sample. For this reason, any closed loop handling concept must find a way to destroy this component. The most promising destruction methods for S_2F_{10} are pyrolysis ⁽¹⁰⁻¹¹⁾ and photolysis ⁽¹²⁾.

Contaminant	SF_6	CF_4	SO_2F_2	SO ₂	HF	SOF_2	SOF_4	SF_4	WF_6	S_2F_{10}
TLV	1000	1000	5	2	2	1.6	0.5	0.1	0.1	0.025
(ppmv)										

Table 3 Threshold Limit Values for Various Gases

Although the use of gas scrubbers and membranes during the manufacture and purification of SF_6 is common practice, the destruction of S_2F_{10} with either pyrolysis or photolysis has yet to be proven on an industrial scale. Solvay Fluor GmbH initiated a study to investigate these techniques to develop a pre-treatment plant for used SF_6 .

The photolysis parameters were chosen based on the fact that certain gases are destroyed at certain wavelengths as shown in Figure 1. Similarly, the pyrolysis parameters were chosen based on literature references stating that S_2F_{10} rapidly decomposes above 250°C (half life = 1.5 seconds).



Figure 1 Wavelength for Destruction of Various Gases using Photolysis

TEST FACILITY

The test facility is shown in Figure 2. Used SF_6 from a cylinder (1) is evaporated in an evaporator (2) and the gas pressure is adjusted via a pressure reducer (3). The SF_6 gas stream is regulated by a fine-adjustment regulating valve (4) and fed either into the photolysis reactor (5) or the pyrolysis reactor (6). The photolysis reactor comprises of a 150 W and 700 W water-cooled 253.7 nm UV lamp with 180 and 520 ml volume operating at 90°C.

For the pyrolysis reactor, a 20 meter spiral shaped copper tube was used with an inner diameter of 2 mm, heated with 750 W heating elements. Temperatures of 350° C are achievable. Lastly, the test facility is equipped with a cooling trap where SF₆ can be liquefied. Gas Chromatography is carried out before and after each test series. The volumetric flow rate, residence time in the reactors (treatment time), temperature and pressure are continuously measured, controlled and

recorded with a data acquisition system. In order to avoid any gas release, the system is kept under slight vacuum.



 $\frac{Figure \ 2}{Test \ Facility \ for \ the \ Investigation \ of \ the \ Destruction \ of \ S_2F_{10}} Using \ Photolysis \ and \ Pyrolysis$

PYROLYSIS RESULTS

The trials were conducted at 250°C and 0.8 bar. The residence time in the reactor was 7.6 seconds at a flow rate of 0.5 l/min. The results are shown in Table 3:

Experiment	CF₄	Air	SF ₆	SO ₂ F ₂	S ₂ F ₁₀	SO ₂
	(%)	(%)	(%)	(ppm)	(ppm)	(ppm)
Base	1.15	1.59	97.17	200	174	300
1	0.95	1.64	95.8		136	610
2	0.91	1.69	97.7		135	1740
3	1.25	1.58	97.02		136	653

Table 4 Impurities Before (Base) and After Pyrolysis

In this experiment, the concentration of S_2F_{10} was only slightly reduced. The literature suggests that S_2F_{10} should be destroyed under these conditions, but this was not the result here. Note that the SO₂ concentration is much higher than the baseline. This is because SO₂ is formed from SO_2F_2 , S_2F_{10} an O₂ during the pyrolysis reaction at 250°C.

PHOTOLOSYS RESULTS

The photolysis trials were conducted using two 700 W ultraviolet lamps at a wavelength of 253.7 nm, at 90°C and 0.8 bar. The residence time of the gas exposed to the lamps was 1.26 seconds

at a flow rate of 0.5 l/min in a reactor vessel volume of 700 ml. The photolysis results are shown in Table 4:

Experiment	CF₄ (%)	Air (%)	SF ₆ (%)	SO ₂ F ₂ (ppm)	S₂F ₁₀ (ppm)	SO ₂ (ppm)
Base	1.15	1.59	97.17	200	174	300
1	1.02	1.52	97.2	BDL	BDL	-
2	0.92	1.55	97.2	BDL	BDL	BDL
3	1.23	1.60	97.8	161	BDL	BDL

BDL = below detection limit

	<u>Table 5</u>	
Impurities	Before (Base) and	After Photolysis

The concentration of S_2F_{10} after the UV treatment in all 3 trials was below the detection limit (detection limit = 5 ppm). In 2 out of the 3 tests, the concentration of SO_2F_2 was also below the detection limit. SF_6 and air was not influenced by the UV treatment. Compared to the pyrolysis trials in this study, photolysis seems to be the most appropriate destruction method for S_2F_{10} .

PILOT PLANT

The various purification processes were arranged in a pilot plant for the pre-treatment of S_2F_{10} , SO_2F_2 , SO_2 , O_2 and N_2 . The pilot plant would ensure adequate pre-treatment of the used SF_6 gas to comply with the ReUse specifications. In other words, the pre-treatment pilot plant would ensure that the used SF_6 gas would comply with the contaminant concentration limits for introducing the gas into the virgin SF_6 production stream. The pilot plant, shown in Figure 3, consists of a photolysis reactor, an alkaline scrubber and a membrane separation unit.



Figure 3 Pilot Plant for the Pre-treatment of Used SF₆ Before Reintroduction in the Virgin SF₆ Production Process Stream

The contaminated SF₆ flows through a pressure reducer to the different purification processes. S₂F₁₀ is efficiently destroyed in the photolysis reactor. The reaction products along with other hydrolysable components are separated from the SF₆ gas stream with an alkaline scrubber while the inert gases such as N_2 and O_2 are separated in a subsequent step using the membrane separation technology.

CONCLUSION

- 1. Photolysis is a viable method for destroying S₂F₁₀ and was implemented in a pilot plant.
- 2. The pilot plant consists of a photolysis reactor to destroy S₂F₁₀, an alkaline scrubber to remove hydrolysable components and a membrane separation unit to remove inert gases.
- 3. The implementation of a purification pre-treatment facility for decomposition products such as S_2F_{10} would complete the SF_6 ReUse program by being able to pre-treat gas that normally would be incinerated, so that it can be introduced in the virgin SF_6 production stream.

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